

Takeshi Kobayashi

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/9110426/publications.pdf>

Version: 2024-02-01

158
papers

3,374
citations

172457

29
h-index

175258

52
g-index

158
all docs

158
docs citations

158
times ranked

2601
citing authors

#	ARTICLE	IF	CITATIONS
1	Piezoelectric MEMS Energy Harvester for Low-Frequency Vibrations With Wideband Operation Range and Steadily Increased Output Power. <i>Journal of Microelectromechanical Systems</i> , 2011, 20, 1131-1142.	2.5	327
2	Investigation of a MEMS piezoelectric energy harvester system with a frequency-widened-bandwidth mechanism introduced by mechanical stoppers. <i>Smart Materials and Structures</i> , 2012, 21, 035005.	3.5	202
3	Piezoelectric MEMS-based wideband energy harvesting systems using a frequency-up-conversion cantilever stopper. <i>Sensors and Actuators A: Physical</i> , 2012, 186, 242-248.	4.1	191
4	A new S-shaped MEMS PZT cantilever for energy harvesting from low frequency vibrations below 30ÂHz. <i>Microsystem Technologies</i> , 2012, 18, 497-506.	2.0	130
5	Development of piezoelectric microcantilever flow sensor with wind-driven energy harvesting capability. <i>Applied Physics Letters</i> , 2012, 100, .	3.3	116
6	Fabric pressure sensor array fabricated with die-coating and weaving techniques. <i>Sensors and Actuators A: Physical</i> , 2012, 184, 57-63.	4.1	112
7	Effect of multi-coating process on the orientation and microstructure of lead zirconate titanate (PZT) thin films derived by chemical solution deposition. <i>Thin Solid Films</i> , 2005, 489, 74-78.	1.8	108
8	Fabrication of Optical Micro Scanner Driven by PZT Actuators. <i>Japanese Journal of Applied Physics</i> , 2005, 44, 7078-7082.	1.5	68
9	Characterization of piezoelectric PZT beam actuators for driving 2D scanning micromirrors. <i>Sensors and Actuators A: Physical</i> , 2010, 162, 336-347.	4.1	60
10	Micromachined piezoelectric ultrasonic transducer with ultra-wide frequency bandwidth. <i>Applied Physics Letters</i> , 2015, 106, .	3.3	60
11	A MEMS-based piezoelectric cantilever patterned with PZT thin film array for harvesting energy from low frequency vibrations. <i>Physics Procedia</i> , 2011, 19, 129-133.	1.2	57
12	A scrape-through piezoelectric MEMS energy harvester with frequency broadband and up-conversion behaviors. <i>Microsystem Technologies</i> , 2011, 17, 1747-1754.	2.0	57
13	Oscillating high-aspect-ratio monolithic silicon nanoneedle array enables efficient delivery of functional bio-macromolecules into living cells. <i>Scientific Reports</i> , 2015, 5, 15325.	3.3	57
14	Van der Pol type self-excited micro-cantilever probe ofÂatomic force microscopy. <i>Nonlinear Dynamics</i> , 2008, 54, 137-149.	5.2	55
15	Relationship between Contact Pressure and Motion Artifacts in ECG Measurement with Electrostatic Flocked Electrodes Fabricated on Textile. <i>Scientific Reports</i> , 2019, 9, 5897.	3.3	51
16	Ultra-Thin Piezoelectric Strain Sensor Array Integrated on a Flexible Printed Circuit Involving Transfer Printing Methods. <i>IEEE Sensors Journal</i> , 2016, 16, 8840-8846.	4.7	49
17	Investigation of geometric design in piezoelectric microelectromechanical systems diaphragms for ultrasonic energy harvesting. <i>Applied Physics Letters</i> , 2016, 108, .	3.3	45
18	Printed strain sensor array for application to structural health monitoring. <i>Smart Materials and Structures</i> , 2017, 26, 105040.	3.5	44

#	ARTICLE	IF	CITATIONS
19	Investigation of Broadband Characteristics of Multi-Frequency Piezoelectric Micromachined Ultrasonic Transducer (MF-pMUT). IEEE Sensors Journal, 2019, 19, 860-867.	4.7	43
20	A 2-D MEMS scanning mirror based on dynamic mixed mode excitation of a piezoelectric PZT thin film S-shaped actuator. Optics Express, 2011, 19, 13812.	3.4	42
21	Microelectromechanical Systems-Based Electrostatic Field Sensor Using Pb(Zr,Ti)O ₃ Thin Films. Japanese Journal of Applied Physics, 2008, 47, 7533.	1.5	41
22	A digital output piezoelectric accelerometer using a Pb(Zr, Ti)O ₃ thin film array electrically connected in series. Smart Materials and Structures, 2010, 19, 105030.	3.5	39
23	A 1-V Operated MEMS Variable Optical Attenuator Using Piezoelectric PZT Thin-Film Actuators. IEEE Journal of Selected Topics in Quantum Electronics, 2009, 15, 1529-1536.	2.9	37
24	Passive piezoelectric DC sensor applicable to one-wire or two-wire DC electric appliances for end-use monitoring of DC power supply. Microsystem Technologies, 2012, 18, 1897-1902.	2.0	37
25	Smart optical microscanner with piezoelectric resonator, sensor, and tuner using Pb(Zr,Ti)O ₃ thin film. Applied Physics Letters, 2007, 90, 183514.	3.3	36
26	Fabrication of piezoelectric microcantilevers using LaNiO ₃ buffered Pb(Zr,Ti)O ₃ thin film. Journal of Micromechanics and Microengineering, 2008, 18, 035007.	2.6	34
27	Developing passive piezoelectric MEMS sensor applicable to two-wire DC appliances with current switching. Micro and Nano Letters, 2012, 7, 68.	1.3	33
28	Flow sensing and energy harvesting characteristics of a wind-driven piezoelectric Pb(Zr _{0.52} , Ti)O ₃ thin film. Journal of Microelectromechanical Systems, 2010, 19, 1370-1379.	1.3	30
29	Degradation in the ferroelectric and piezoelectric properties of Pb(Zr,Ti)O ₃ thin films derived from a MEMS microfabrication process. Journal of Micromechanics and Microengineering, 2007, 17, 1238-1241.	2.6	29
30	Passive piezoelectric single-side MEMS DC current sensor with five parallel PZT plates applicable to two-wire DC electric appliances without using cord separator. Microsystem Technologies, 2013, 19, 923-927.	2.0	29
31	Wafer scale lead zirconate titanate film preparation by sol-gel method using stress balance layer. Thin Solid Films, 2006, 515, 1506-1510.	1.8	28
32	Sensing Property of Self-Sensitive Piezoelectric Microcantilever Utilizing Pb(Zr _{0.52} /Ti _{0.48})O ₃ Thin Film and LaNiO ₃ Oxide Electrode. Japanese Journal of Applied Physics, 2007, 46, 7073-7078.	1.5	28
33	Piezoelectric Optical Micro Scanner with Built-in Torsion Sensors. Japanese Journal of Applied Physics, 2007, 46, 2781-2784.	1.5	27
34	A Piezoelectric-Driven Three-Dimensional MEMS VOA Using Attenuation Mechanism With Combination of Rotational and Translational Effects. Journal of Microelectromechanical Systems, 2010, 19, 1370-1379.	2.5	27
35	Integrated piezoelectric direct current sensor with actuating and sensing elements applicable to two-wire dc appliances. Measurement Science and Technology, 2013, 24, 125109.	2.6	27
36	Passive MEMS DC Electric Current Sensor: Part I—Theoretical Considerations. IEEE Sensors Journal, 2017, 17, 1230-1237.	4.7	27

#	ARTICLE	IF	CITATIONS
37	Novel piezoelectric actuation mechanism for a gimbal-less mirror in 2D raster scanning applications. <i>Journal of Micromechanics and Microengineering</i> , 2011, 21, 075001.	2.6	25
38	A digital output accelerometer using MEMS-based piezoelectric accelerometers and arrayed CMOS inverters with satellite capacitors. <i>Smart Materials and Structures</i> , 2011, 20, 065017.	3.5	25
39	Investigation of piezoelectric driven MEMS mirrors based on single and double S-shaped PZT actuator for 2-D scanning applications. <i>Sensors and Actuators A: Physical</i> , 2012, 184, 149-159.	4.1	25
40	Developing integrated piezoelectric direct current sensor with actuating and sensing elements. <i>Micro and Nano Letters</i> , 2013, 8, 858-860.	1.3	25
41	Impact of pulse poling on static and dynamic ferroelastic-domain contributions in tetragonal Pb(Ti) _{1-x} (Zr) _x O ₃ thin films. <i>Journal of Applied Physics</i> , 2013, 114, 074105.	2.5	25
42	Mechanoporation of living cells for delivery of macromolecules using nanoneedle array. <i>Journal of Bioscience and Bioengineering</i> , 2016, 122, 748-752.	2.2	25
43	A New Cell Separation Method Based on Antibody-Immobilized Nanoneedle Arrays for the Detection of Intracellular Markers. <i>Nano Letters</i> , 2017, 17, 7117-7124.	9.1	25
44	Printed strain sensor with temperature compensation and its evaluation with an example of applications in structural health monitoring. <i>Japanese Journal of Applied Physics</i> , 2017, 56, 05EC02.	1.5	24
45	Passive MEMS DC Electric Current Sensor: Part II—Experimental Verifications. <i>IEEE Sensors Journal</i> , 2017, 17, 1238-1245.	4.7	24
46	Thin-film flexible sensor for omnidirectional strain measurements. <i>Sensors and Actuators A: Physical</i> , 2017, 263, 391-397.	4.1	24
47	Manufacturing process for piezoelectric strain sensor sheet involving transfer printing methods. <i>Japanese Journal of Applied Physics</i> , 2015, 54, 10ND08.	1.5	23
48	Ultra-Low Power Event-Driven Wireless Sensor Node Using Piezoelectric Accelerometer for Health Monitoring. <i>Japanese Journal of Applied Physics</i> , 2009, 48, 070222.	1.5	22
49	An electrostatic field sensor operated by self-excited vibration of MEMS-based self-sensitive piezoelectric microcantilevers. <i>Sensors and Actuators A: Physical</i> , 2013, 198, 87-90.	4.1	22
50	Broadband MEMS shunt switches using PZT/HfO ₂ multi-layered high k dielectrics for high switching isolation. <i>Sensors and Actuators A: Physical</i> , 2005, 121, 275-281.	4.1	20
51	Direct Delivery of Cas9-sgRNA Ribonucleoproteins into Cells Using a Nanoneedle Array. <i>Applied Sciences (Switzerland)</i> , 2019, 9, 965.	2.5	19
52	Fabrication and performance of a flat piezoelectric cantilever obtained using a sol-gel derived PZT thick film deposited on a SOI wafer. <i>Smart Materials and Structures</i> , 2006, 15, S137-S140.	3.5	18
53	A fatigue test method for Pb(Zr,Ti)O ₃ thin films by using MEMS-based self-sensitive piezoelectric microcantilevers. <i>Journal of Micromechanics and Microengineering</i> , 2008, 18, 115007.	2.6	18
54	Vibration-energy-harvesting properties of hydrothermally synthesized (K,Na)NbO ₃ films deposited on flexible metal foil substrates. <i>Japanese Journal of Applied Physics</i> , 2015, 54, 10ND06.	1.5	18

#	ARTICLE	IF	CITATIONS
55	Concentric Array of Printed Strain Sensors for Structural Health Monitoring. <i>Sensors</i> , 2020, 20, 1997.	3.8	18
56	Influence of pulse poling on the piezoelectric property of Pb(Zr _{0.52} Ti _{0.48})O ₃ thin films. <i>AIP Advances</i> , 2014, 4, 117116.	1.3	17
57	Design of piezoelectric MEMS cantilever for low-frequency vibration energy harvester. <i>Japanese Journal of Applied Physics</i> , 2016, 55, 06GP14.	1.5	17
58	Deflection of wafers and cantilevers with Pt/LNO/PZT/LNO/Pt/Ti/SiO ₂ multilayered structure. <i>Thin Solid Films</i> , 2008, 516, 5272-5276.	1.8	16
59	A 2-D MEMS Scanning Mirror Using Piezoelectric PZT Beam Actuators. <i>Procedia Chemistry</i> , 2009, 1, 1303-1306.	0.7	16
60	Preparation and characterization of wafer scale lead zirconate titanate film for MEMS application. <i>Sensors and Actuators A: Physical</i> , 2007, 139, 152-157.	4.1	15
61	Low speed piezoelectric optical microscanner actuated by piezoelectric microcantilevers using LaNiO ₃ buffered Pb(Zr,Ti)O ₃ thin film. <i>Smart Materials and Structures</i> , 2009, 18, 065008.	3.5	15
62	Development of a MEMS DC electric current sensor applicable to two-wire electrical appliance cord. , 2011, , .		15
63	Effects of Bipolar Pulse Poling on the Ferroelectric and Piezoelectric Properties of Tetragonal Composition Pb(Zr _{0.3} ,Ti _{0.7})O ₃ Thin Films on Microelectromechanical Systems Microcantilevers. <i>Japanese Journal of Applied Physics</i> , 2013, 52, 09KA01.	1.5	14
64	S-shape spring sensor: Sensing specific low-frequency vibration by energy harvesting. <i>Review of Scientific Instruments</i> , 2016, 87, 085005.	1.3	14
65	Printed Strain Sensors Based on an Intermittent Conductive Pattern Filled with Resistive Ink Droplets. <i>Sensors</i> , 2020, 20, 4181.	3.8	14
66	<i>In situ</i> Observation of the Fatigue-Free Piezoelectric Microcantilever by Two-Dimensional X-ray Diffraction. <i>Japanese Journal of Applied Physics</i> , 2009, 48, 09KA03.	1.5	13
67	Low-Voltage Driven MEMS VOA Using Torsional Attenuation Mechanism Based on Piezoelectric Beam Actuators. <i>IEEE Photonics Technology Letters</i> , 2010, 22, 1355-1357.	2.5	13
68	Flexible fabric keyboard with conductive polymer-coated fibers. , 2011, , .		13
69	A piezoelectric flow sensor for use as a wake-up switch for a wireless sensor network node. <i>Mechatronics</i> , 2013, 23, 893-897.	3.3	13
70	Highly sensitive piezoelectric micromachined ultrasonic transducer (pMUT) operated in air. , 2016, , .		13
71	Tunable Optical Microscanner Driven by Piezoelectric Actuator. <i>Japanese Journal of Applied Physics</i> , 2007, 46, 6429-6432.	1.5	12
72	Quality factor of micro cantilevers transduced by piezoelectric lead zirconate titanate film. <i>Microsystem Technologies</i> , 2007, 13, 1517-1522.	2.0	12

#	ARTICLE	IF	CITATIONS
73	The influence of DC bias on the displacement and sensor output of self-sensitive piezoelectric microcantilevers. Journal of Micromechanics and Microengineering, 2008, 18, 035025.	2.6	12
74	In-Plane Lattice Strain Evaluation in Piezoelectric Microcantilever by Two-Dimensional X-ray Diffraction. Japanese Journal of Applied Physics, 2008, 47, 7537.	1.5	12
75	Unique Activity-Meter with Piezoelectric Poly(vinylidene difluoride) Films and Self Weight of the Sensor Nodes. Japanese Journal of Applied Physics, 2013, 52, 09KD15.	1.5	12
76	Carbon-based printed strain sensor array for remote and automated structural health monitoring. Smart Materials and Structures, 2020, 29, 105022.	3.5	12
77	Highly sensitive piezoelectric micromachined ultrasonic transducer operated in air. Micro and Nano Letters, 2016, 11, 558-562.	1.3	11
78	Development of Flexible Piezoelectric Strain Sensor Array. Electrical Engineering in Japan (English) Tj ETQq0 0 0 rgBT /Overlock 10 Tf 50	0.4	11
79	Investigation of Piezoelectric MEMS-based Wideband Energy Harvesting System with Assembled Frequency-up- conversion Mechanism. Procedia Engineering, 2011, 25, 725-728.	1.2	10
80	Printed strain sensors for early damage detection in engineering structures. Japanese Journal of Applied Physics, 2018, 57, 05GD05.	1.5	10
81	A Digital Output Piezoelectric Accelerometer using Pattenmed Pb(Zr, Ti)O<inf>3</inf> Thin Films Electrically Connected in Series. , 2009, , .		9
82	Plastic-scale-model assembly of ultrathin film MEMS piezoresistive strain sensor with conventional vacuum-suction chip mounter. Scientific Reports, 2019, 9, 1893.	3.3	9
83	Impact of Reflow on the Output Characteristics of Piezoelectric Microelectromechanical System Devices. Japanese Journal of Applied Physics, 2012, 51, 09LD11.	1.5	9
84	A piezoelectric cantilever-type differential pressure sensor for a low standby power trigger switch. Journal of Micromechanics and Microengineering, 2013, 23, 125023.	2.6	8
85	Simulation of an ultralow-power power management circuit for MEMS cantilever piezoelectric vibration energy harvesters. Japanese Journal of Applied Physics, 2016, 55, 10TA06.	1.5	8
86	Simulation and fabrication of a MEMS optical scanner device considering deformation caused by internal stress. Japanese Journal of Applied Physics, 2016, 55, 10TA11.	1.5	8
87	All Polymer Piezoelectric Film for the Application to Low Resonance Frequency Energy Harvester. Procedia Engineering, 2011, 25, 203-206.	1.2	7
88	Impact of Reflow on the Output Characteristics of Piezoelectric Microelectromechanical System Devices. Japanese Journal of Applied Physics, 2012, 51, 09LD11.	1.5	7
89	Photovoltaic Effect of Crystalline-Oriented Lead Lanthanum Zirconate Titanate in Layered Film Structure. Japanese Journal of Applied Physics, 2006, 45, 9115-9118.	1.5	6
90	The effect of heat-treatment conditions on mechanical and morphological properties of a FIB-milled glassy carbon mold with micro patterns. Journal of Micromechanics and Microengineering, 2006, 16, 1277-1284.	2.6	6

#	ARTICLE	IF	CITATIONS
91	Piezoelectric MEMS switch to activate event-driven wireless sensor nodes. Smart Materials and Structures, 2013, 22, 095001.	3.5	6
92	High-efficiency MOSFET bridge rectifier for AlN MEMS cantilever vibration energy harvester. Japanese Journal of Applied Physics, 2017, 56, 04CC03.	1.5	6
93	Sol-gel deposition of PZT thick film on Pt/Ti/SOI substrate and application to 2D micro scanning mirror. , 2004, , .		5
94	Investigation of a Piezoelectric Driven MEMS Mirror based on Single S-shaped PZT Actuator. Procedia Engineering, 2011, 25, 701-704.	1.2	5
95	Piezoelectric strain sensor array fabricated by transfer printing methods. , 2015, , .		5
96	Soft-rubber-packaged Pb(Zr,Ti)O ₃ MEMS touch sensors for human-machine interface applications. Japanese Journal of Applied Physics, 2017, 56, 04CC04.	1.5	5
97	Fabrication of an ultrathin lead zirconate titanate mirror device mounted on flexible substrate. Japanese Journal of Applied Physics, 2017, 56, 10PF11.	1.5	5
98	Microneedle Array-Assisted, Direct Delivery of Genome-Editing Proteins Into Plant Tissue. Frontiers in Plant Science, 0, 13, .	3.6	5
99	Preparation and Its Photovoltaic Effect of Ferroelectric Film. Key Engineering Materials, 2006, 301, 193-196.	0.4	4
100	Combined Device of Optical Microdisplacement Sensor and PZT-Actuated Micromirror. , 2007, , .		4
101	Influence of Pt/Ti Sputtering Temperature on the Orientation of CSD-Derived Pb(Zr _{0.52} Ti _{0.48})O ₃ Thin Films. Ferroelectrics, 2007, 357, 233-242.	0.6	4
102	A wake-up switch using a piezoelectric differential pressure sensor. , 2013, , .		4
103	Growth of (111) One-Axis-Oriented Bi(Mg _{1/2} Ti _{1/2})O ₃ Films on (100)Si Substrates. Japanese Journal of Applied Physics, 2013, 52, 04CH09.	1.5	4
104	Wireless vibration sensing system powered by a piezoelectric MEMS vibration energy harvester. , 2016, , .		4
105	Development of ultra-thin MEMS micro mirror device. , 2017, , .		4
106	Wearable muscle training and monitoring device. , 2018, , .		4
107	Development of energy harvesting MEMS vibration device sensor with wideband response function in low-frequency domain. Microsystem Technologies, 2022, 28, 1389-1397.	2.0	4
108	Practical Evaluation of Printed Strain Sensors Based on Long-Term Static Strain Measurements. Sensors, 2021, 21, 4812.	3.8	4

#	ARTICLE	IF	CITATIONS
109	Wideband and high reliability RF-MEMS switches using PZT/HfO ₂ / multi-layered high K dielectrics. , 0, ,		3
110	Development of 1D Optical Micro Scanner Driven by Piezoelectric Actuators. , 2005, , 789.		3
111	Novel MEMS-based thermometer with low power consumption for health-monitoring network application. Proceedings of SPIE, 2007, 6800, 390.	0.8	3
112	MEMS-based piezoelectric micro cantilever using LaNiO ₃ / buffered PZT thin film. Applications of Ferroelectrics, IEEE International Symposium on, 2007, , .	0.0	3
113	A Digital Output Accelerometer Using MEMS-based Piezoelectric Accelerometer Connected to Parallel CMOS Circuit. Procedia Engineering, 2010, 5, 1071-1074.	1.2	3
114	A piezoelectric cantilever with a Helmholtz resonator as a sound pressure sensor. Journal of Micromechanics and Microengineering, 2013, 23, 114003.	2.6	3
115	Crystal Structure Change with Applied Electric Field for (100)/(001)-oriented Polycrystalline Lead Zirconate Titanate Films. Materials Research Society Symposia Proceedings, 2013, 1507, 1.	0.1	3
116	A Silicon Disk with Sandwiched Piezoelectric Springs for Ultra-low Frequency Energy Harvesting. Journal of Physics: Conference Series, 2015, 660, 012093.	0.4	3
117	Ultra-thin piezoelectric strain sensor array integrated on flexible printed circuit for structural health monitoring. , 2016, , .		3
118	MEMS based piezoelectric ultrasonic energy harvester for self-powered under-water applications. , 2016, , .		3
119	Development of wide-band low-frequency MEMS vibration energy harvester for utility infrastructure core monitoring system. , 2017, , .		3
120	Large-scale printed strain sensors based on carbon ink incorporated into an intermittent conductive silver pattern. Japanese Journal of Applied Physics, 2021, 60, SBBM01.	1.5	3
121	Formation and its characteristics of PLZT layered film structure for transducers. , 2004, , .		2
122	DEVELOPMENT OF SELF-SENSITIVE PIEZOELECTRIC CANTILEVER UTILIZING PZT THIN FILM DEPOSITED ON SOI WAFER. Integrated Ferroelectrics, 2007, 89, 116-122.	0.7	2
123	A 3-D MEMS VOA using translational attenuation mechanism based on piezoelectric PZT thin film actuators. Procedia Engineering, 2010, 5, 613-616.	1.2	2
124	Wafer-Scale MEMS Technology of New Vertically Laminated Cantilevers. Procedia Engineering, 2011, 25, 677-680.	1.2	2
125	AlN cantilever for differential pressure sensor. , 2013, , .		2
126	A smart, intermittent driven particle sensor with an airflow change trigger using a lead zirconate titanate (PZT) cantilever. Measurement Science and Technology, 2014, 25, 025103.	2.6	2

#	ARTICLE	IF	CITATIONS
127	Characterizations of epitaxial $\text{Bi}(\text{Mg}_{1/2}\text{Ti}_{1/2})\text{O}_3$ and $\text{Bi}(\text{Zn}_{1/2}\text{Ti}_{1/2})\text{O}_3$ solid solution films grown by pulsed laser deposition. Japanese Journal of Applied Physics, 2014, 53, 05FE06.		2
128	Activation of piezoelectric property of PZT thin films by pulse poling. Journal of Physics: Conference Series, 2014, 557, 012130.	0.4	2
129	Broadband piezoelectric micromachined ultrasonic transducer (pMUT) using mode-merged design. , 2015, , .		2
130	Developing MEMS DC electric current sensor for end-use monitoring of DC power supply: Part V - corresponding relationship between polarization and output voltage. , 2015, , .		2
131	Mechanomyogram measurement by lead zirconate titanate-based acoustic sensor. Japanese Journal of Applied Physics, 2018, 57, 11UD09.	1.5	2
132	Ultra-thin PZT/Si chip integrated on paper substrates. Japanese Journal of Applied Physics, 2021, 60, SFFB12.	1.5	2
133	Ultra-low Power MEMS Activity Sensor for Wireless Health Monitoring System. IEEJ Transactions on Sensors and Micromachines, 2014, 134, 70-71.	0.1	2
134	Formation and its Photovoltaic Effect of Layered Ferroelectric Film Structure. Key Engineering Materials, 2004, 269, 241-244.	0.4	1
135	Fabrication of Flat PZT Cantilevers through MEMS Technologies and Application to Optical MEMS. Key Engineering Materials, 2006, 301, 37-40.	0.4	1
136	Photovoltaic properties of ferroelectrics and their applications to optical sensor. , 2007, 6800, 232.		1
137	High Throughput Fabrication Process for Polymer MEMS using Molding and Printed Pattern Transfer. Procedia Engineering, 2011, 25, 876-879.	1.2	1
138	A MEMS-based wideband piezoelectric energy harvester system using mechanical stoppers. , 2011, , .		1
139	Piezoelectric PVDF film switch to activate event-driven system for chicken health monitoring. , 2014, , .		1
140	Printed carbon-based sensors array for measuring 2D dynamic strain distribution and application in structural health monitoring. , 2016, , .		1
141	A passive position- and pose-free current sensor. , 2017, , .		1
142	Developing MEMS DC electric current sensor for end-use monitoring of DC power supply: Part VI "Corresponding relationship between sensitivity and magnetic induction. , 2017, , .		1
143	Development of Flexible Haptic Device Based on Ultra-Thin PZT/Silicon Vibrator Array. , 2021, , .		1
144	All Polymer Piezoelectric Film for Low Resonance Frequency Vibration Driven Energy Harvesting Application. IEEJ Transactions on Sensors and Micromachines, 2013, 133, 285-289.	0.1	1

#	ARTICLE	IF	CITATIONS
145	Development of Flexible Piezoelectric Strain Sensor Array. IEEJ Transactions on Sensors and Micromachines, 2017, 137, 438-443.	0.1	1
146	Printed sensors for damage detection in large engineering structures. , 2022, , .		1
147	An integrated fabrication of sol-gel derived PZT thick films and SOI for 2D optical micromirror. , 0, , .		0
148	Photovoltaic effect of ferroelectric PLZT in a layered and preferentially oriented film. , 2005, 6035, 190.		0
149	Photovoltaic Effect with the Structural Control and its Application to the Optical Sensor. Key Engineering Materials, 2006, 320, 61-64.	0.4	0
150	MEMS VOA based on torsional and bending attenuation mechanisms using piezoelectric cantilever integrated with 1×10 PZT thin film actuators. , 2010, , .		0
151	A 2-D raster scanning mirror driven by piezoelectric cantilever actuator array in combinational mode — Bending and torsional. , 2011, , .		0
152	Smart ping pong racket by ultrathin piezoelectric strain sensor array. , 2018, , .		0
153	Fabrication and Evaluation of MEMS Piezoelectric Vibration Sensor with Energy Harvesting Function. , 2019, , .		0
154	Flexible Film Loudspeaker Based on Piezoelectric PZT/Si Ultra-Thin MEMS Chips. , 2021, , .		0
155	Fabrication Process and Evaluation of Printed Strain Sensors for Detection of Maximum Strain Direction. , 2021, , .		0
156	Wearable MEMS Sensor Nodes for Animal Health Monitoring System. , 2022, , 283-305.		0
157	MEMS-based microsensors using piezoelectric thin films as sensors and actuators. , 2014, , 37-47.		0
158	Flexible Parametric Speaker with Ultra-Thin PZT/Si MEMS Chips Integrated On Paper Substrate. , 2022, , .		0